

## Patent Abstracts of Japan

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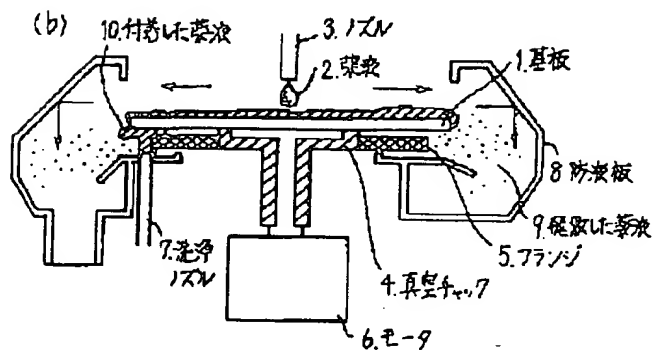
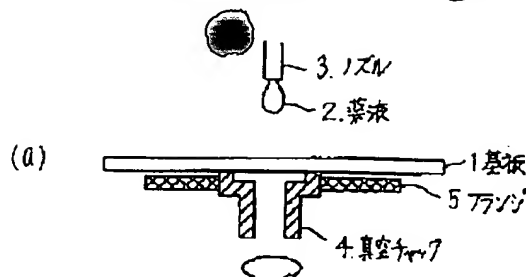
TITLE : CHEMICAL COATING DEVICE



ABSTRACT : PURPOSE: To obtain for preventing a chemical, such as a resist liquid, from penetrating into vacuum chuck for the improvement of a chemical spin coating device for the resist liquid or the like.

CONSTITUTION: In a chemical coating device of a structure, wherein a chemical 2 is dripped or sprayed on the surface of a substrate 1 through a nozzle 3 and the chemical 2 is spin coated on the substrate 1, flanges 5, which have a diameter smaller than the outer diameter of the substrate 1 and are made the gaps between the flanges 5 and a vacuum chuck 4 approach to an interval of such the extent that the chemical 2 does not creep in the chuck 4 through the gaps, are respectively provided on the side surfaces of the chuck 4 for sucking and fixing the substrate 1.

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